


<b>Search Notes</b>  	<b>Application/Control No.</b>  10549438	<b>Applicant(s)/Patent Under Reexamination</b>  KUNZE ET AL.
	<b>Examiner</b>  Wai-Sing Louie	<b>Art Unit</b>  2814

SEARCHED			
Class	Subclass	Date	Examiner
257	415,419,467,469	3/6/08	WSL
257	48	3/7/08	WSL
438	50,52	3/6/08	WSL
257	48,415,419,467,469	12/4/08	WSL

SEARCH NOTES		
Search Notes	Date	Examiner
MEMS, micro-electromechanical, group III nitride, silicon substrate, schottky contact	3/7/08	WSL
Temperature/pressure sensor, cavity, diaphragm, cover layer, electrode, gallium nitride	12/4/08	WSL

INTERFERENCE SEARCH			
Class	Subclass	Date	Examiner
257	48, 415,419,467	12/4/08	WSL

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